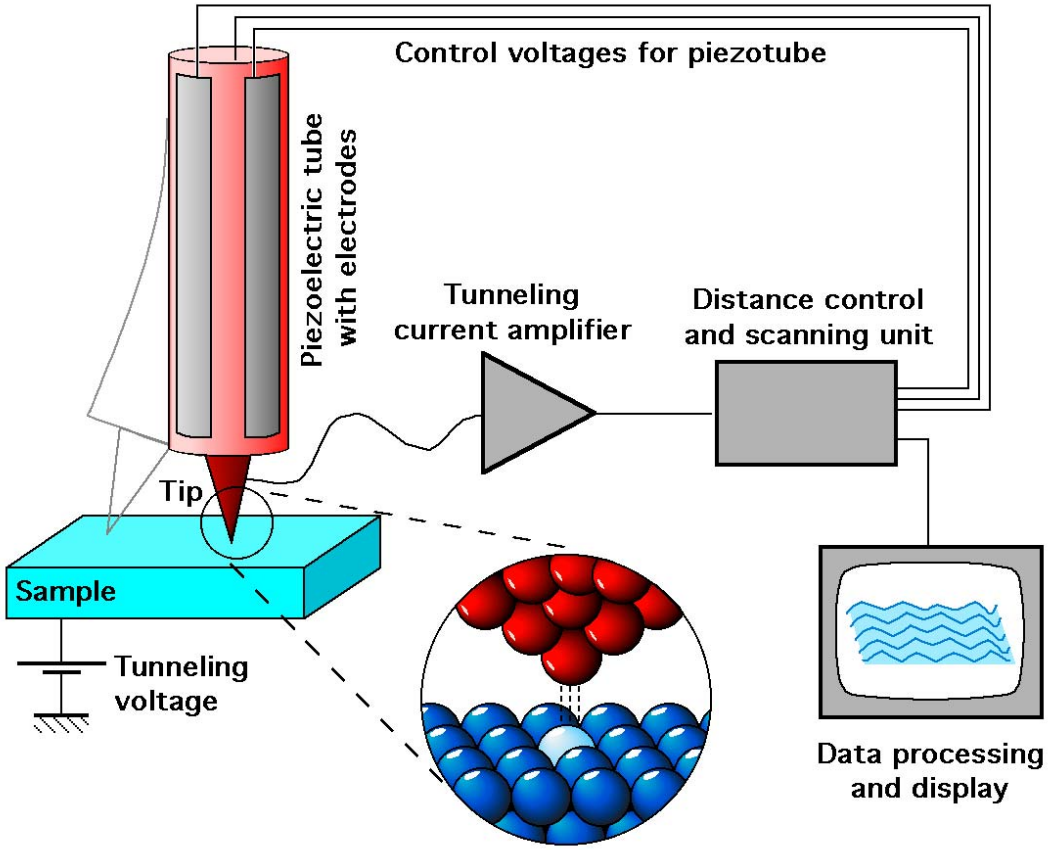
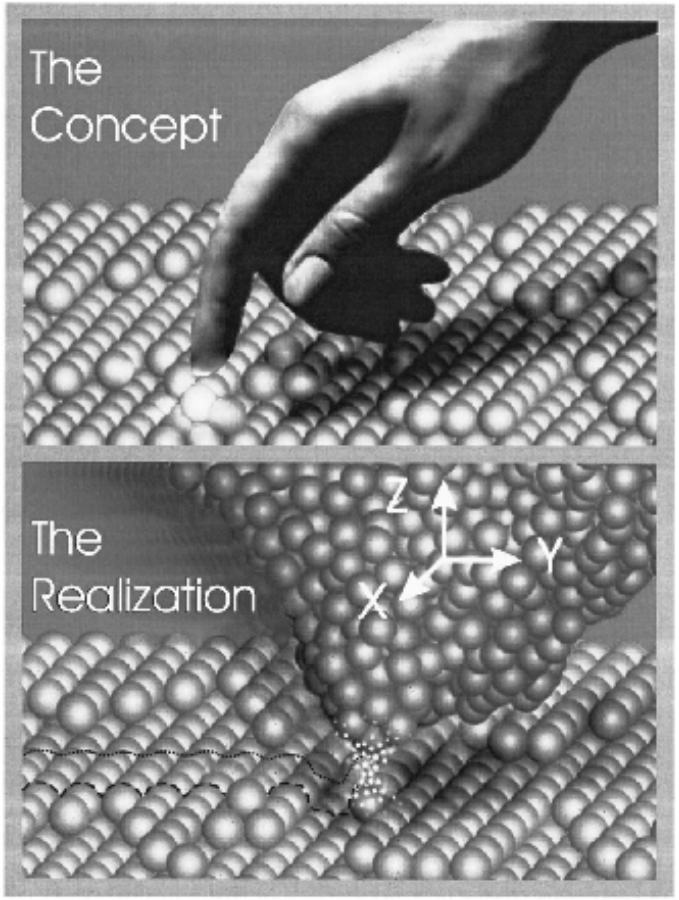
Scanning Tunneling Microscopy



References:

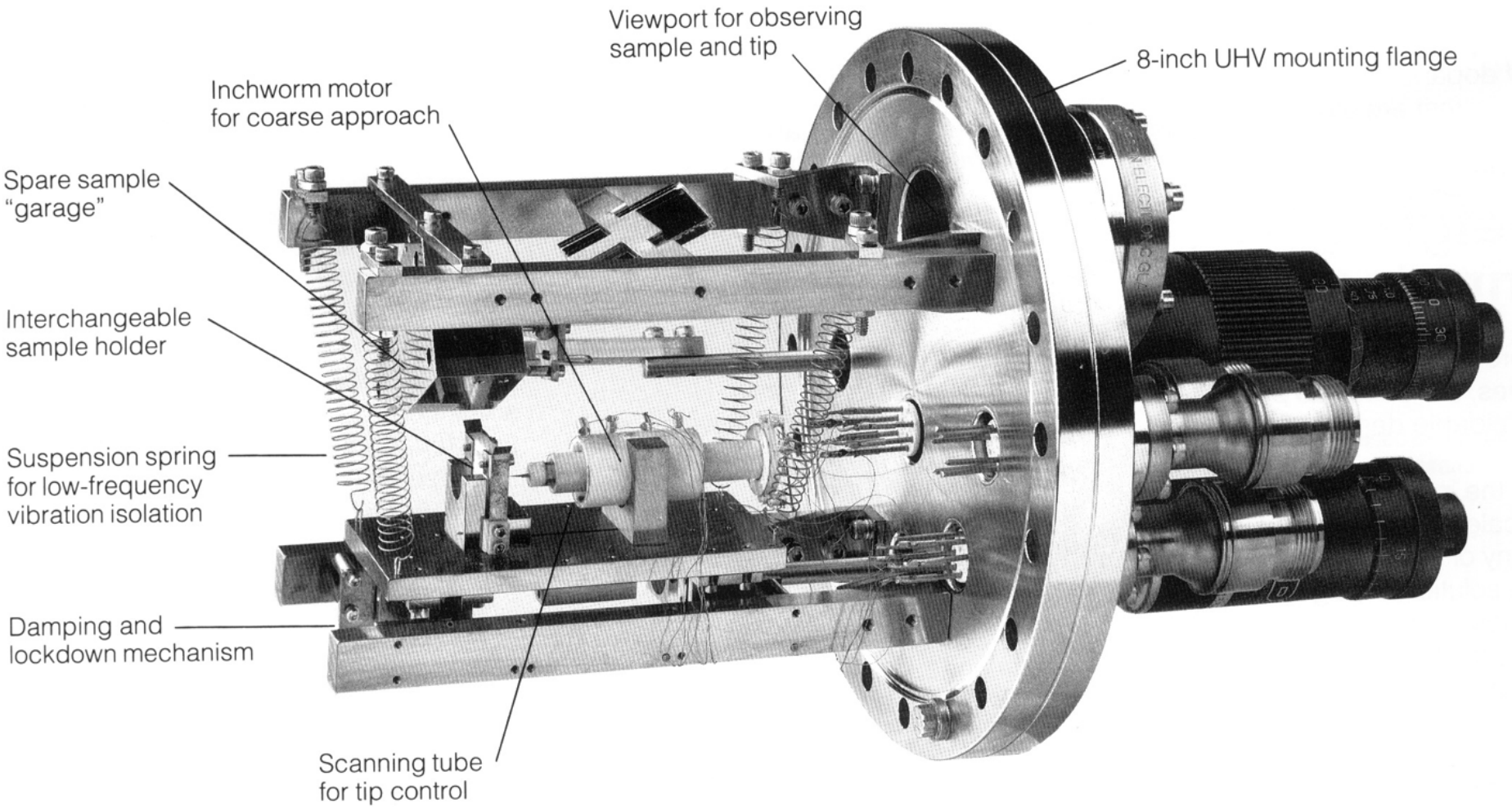
1. G. Binnig, H. Rohrer, C. Gerber, and Weibel, Phys. Rev. Lett. **49**, 57 (1982); and ibid **50**, 120 (1983).
2. J. Chen, *Introduction to Scanning Tunneling Microscopy*, New York, Oxford Univ. Press (1993).

Concept: Eye and Finger

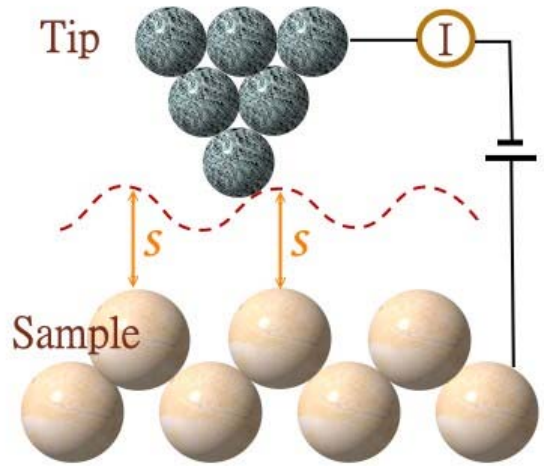


G. Binnig and and H. Rohrer, *Rev. of Mod. Phys.* **71**, S324-S330 (1999).

Ultra-High Vacuum Scanning Tunneling Microscope

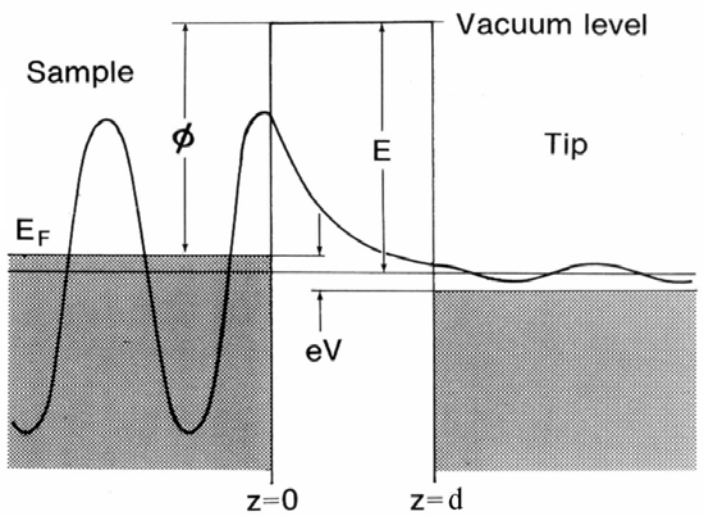


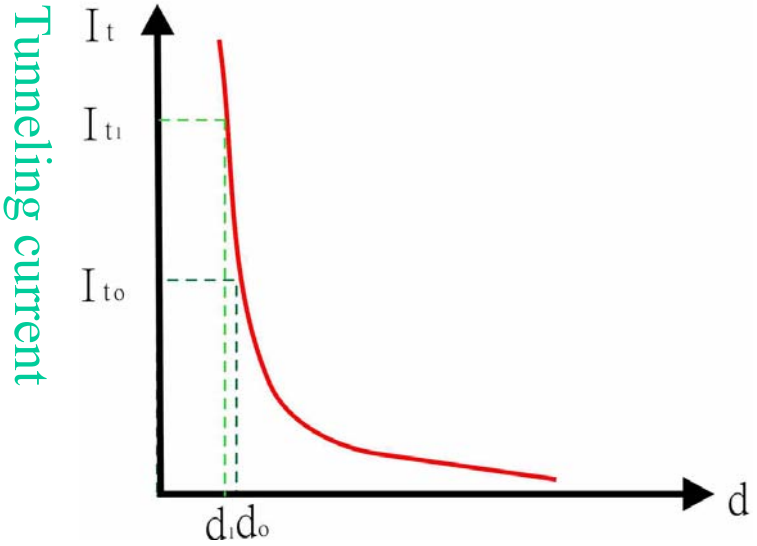
Theory of STM



Constant Current Mode

Tunneling





Tunneling current I_t

$I_t \propto (V/d)\exp(-A\phi^{1/2}d)$

$A = 1.025\ (eV)^{-1/2}Å^{-1}$

$\phi \sim 4 - 5$ eV

d decreases by 1 Å,

I_t will be increased by ~10 times.

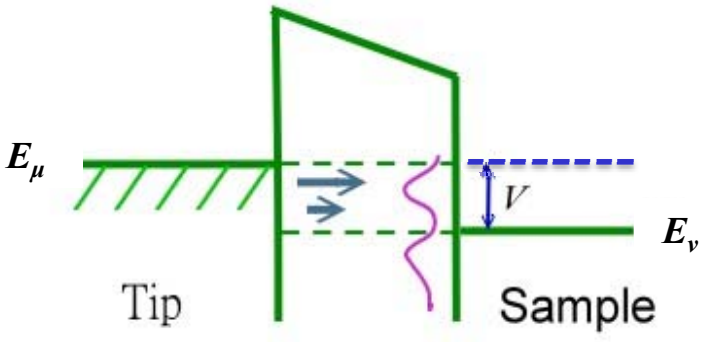
Tunneling current

$$I_{T\to S} = \frac{2\pi e}{\hbar}\sum_{\mu\nu} f(E_\mu)\left[1 - f(E_\nu + eV)\right]\left|M_{\mu\nu}\right|^2 \delta(E_\mu - E_\nu - eV)$$

where f(E) is Fermi function,

$E_{\mu,\nu}$ is the energy of state, where μ and ν run over all the states of the tip and surface,

$M_{\mu\nu}$ is tunneling matrix element.



$$M_{\mu\nu} \equiv \frac{\hbar^2}{2m}\int d\vec{s}\left(\psi_\mu^* \nabla\psi_\nu - \psi_\nu \nabla\psi_\mu^*\right)$$

where ψ_μ is the wave function, and the integral is over any plane in the barrier region.

$$I = I_{T\to S} - I_{S\to T}$$
$$= A'\int_{-\infty}^{\infty} \rho_T(E)\rho_S(E+eV)\left|M(E)\right|^2\left[f(E) - f(E+eV)\right]dE$$

where ρ_S and ρ_T are the densities of states in the sample and the tip, respectively.

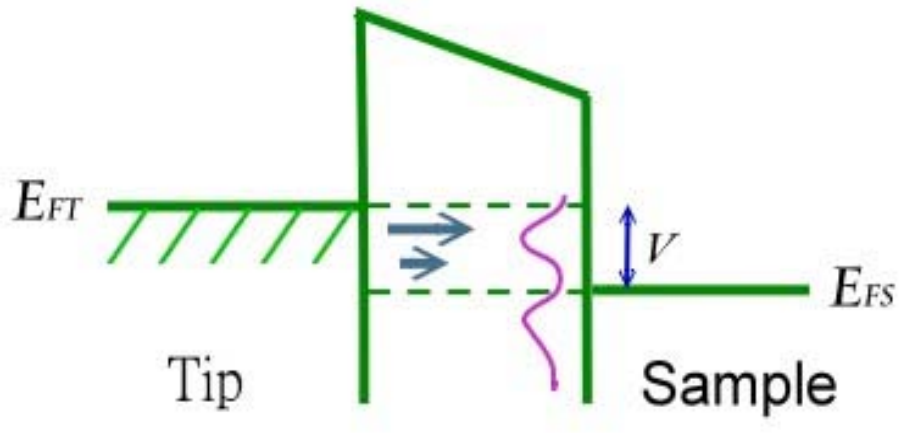
Tunneling current

$$I \equiv A' \int_{-\infty}^{\infty} \rho_T(E)\rho_S(E+eV)\left|M(E)\right|^2 \left[f(E)-f(E+eV)\right]dE$$

Transmission probability of the electron

$$M(E) = \exp\left[-A\phi^{\frac{1}{2}}S\right]$$

Usually, we assume ρ_T is featureless (ie. $\rho_T \approx const.$), and the sample electronics states dominate the tunnel spectra.



However, the tips might have effect on the tunnel spectra, if

1. we have atomically sharp tips ,or
2. the tip has picked up a foreign atom.

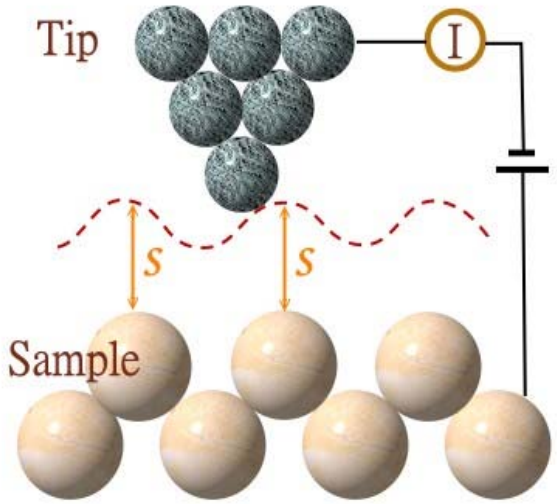
In the low-voltage limit

$$I \propto V \rho_S(\tilde{r}_t; E_F)\rho_t(E_F)$$

where $\rho_S(\tilde{r}_t; E_F)$ is the surface density of states of the sample at the center of the tip($\tilde{r}_t$),

$$\rho_S(\tilde{r}; E) \equiv \sum_\nu |\psi_\nu(\tilde{r})|^2 \delta(E_\nu - E)$$

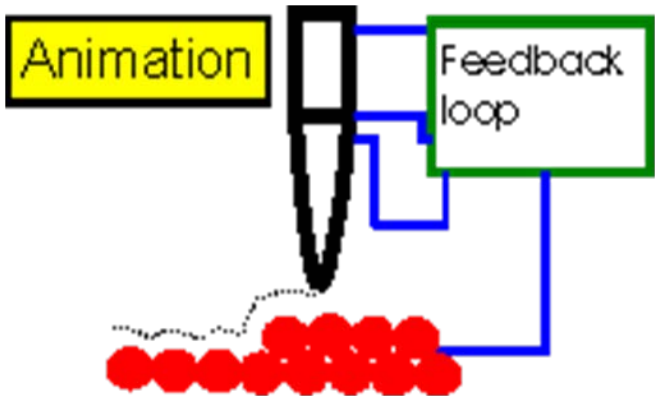
$\rho_t(E_F)$ is the density of states of the tip at the Fermi level and is often regarded as a constant.



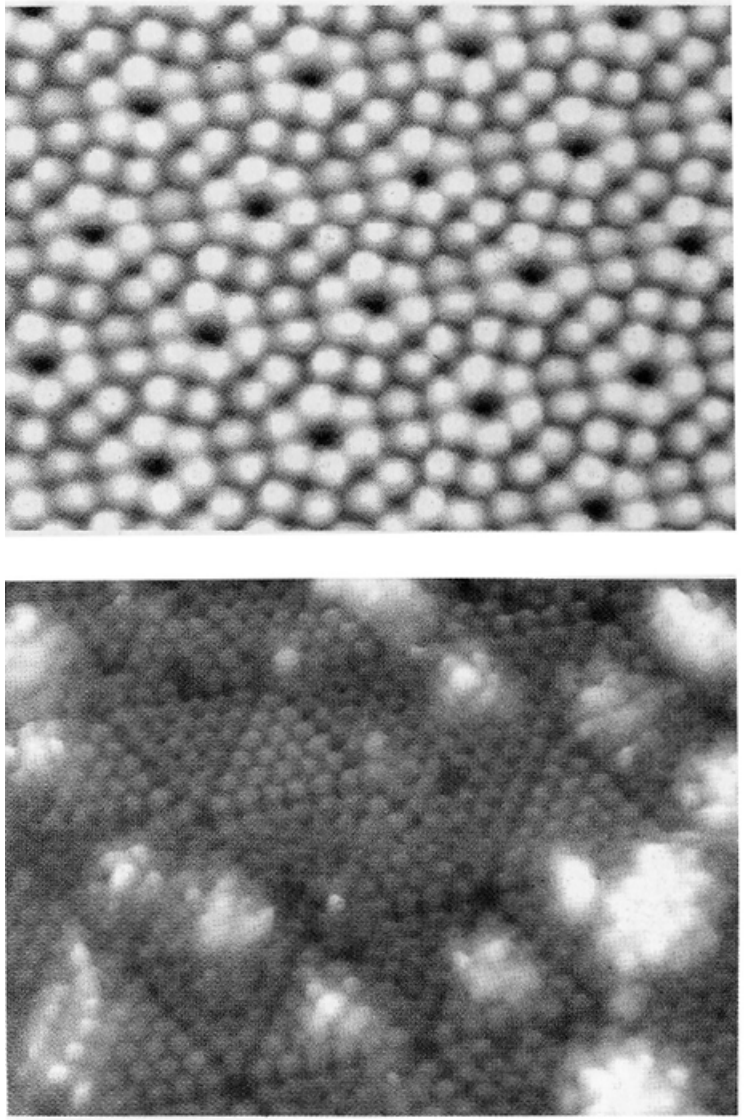
Constant Current Mode

Modes of Operation

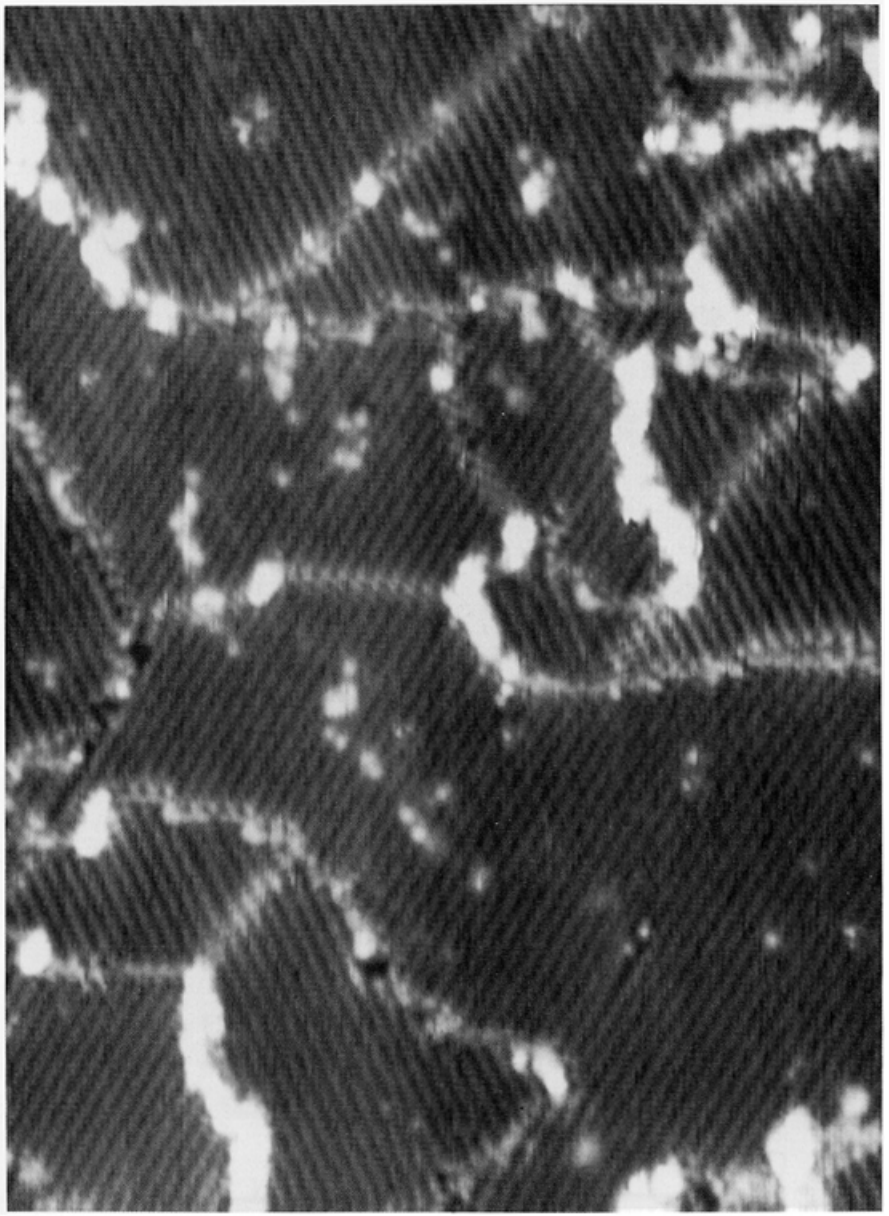
1. **Constant Current Mode**
   By using a feedback loop the tip is vertically adjusted in such a way that the current always stays constant. As the current is proportional to the local density of states, the tip follows a contour of a constant density of states during scanning. A kind of a topographic image of the surface is generated by recording the vertical position of the tip.



Si(111)-(7x7)

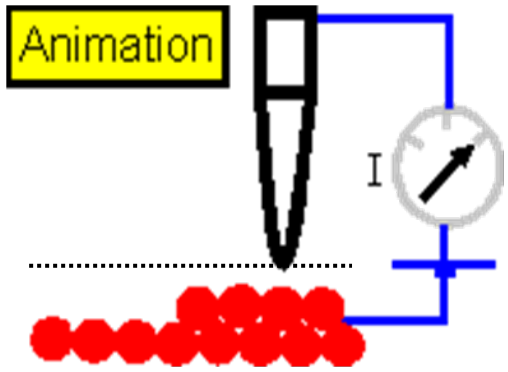


Si(111)-2x1



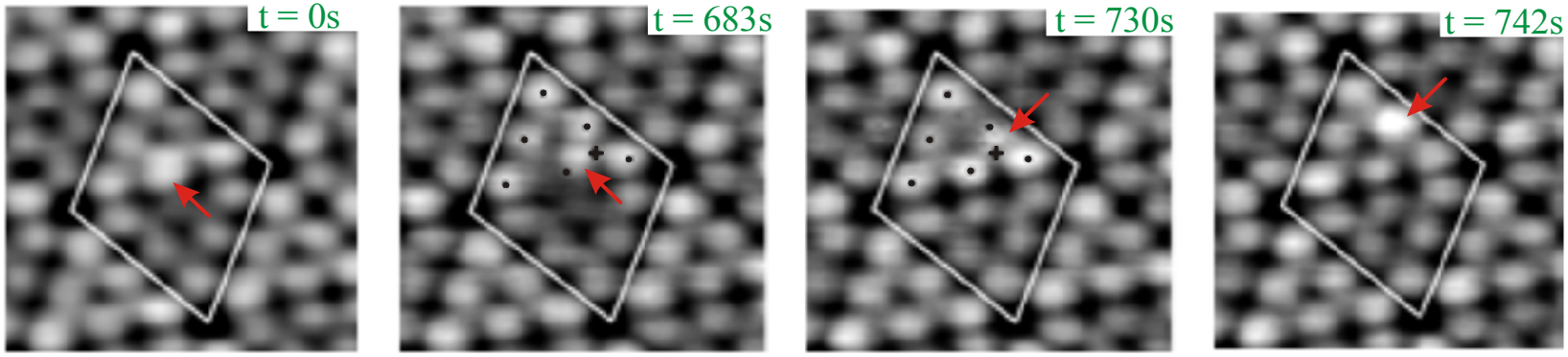
2. Constant Height Mode

In this mode the vertical position of the tip is not changed, equivalent to a slow or disabled feedback. The current as a function of lateral position represents the surface image. This mode is only appropriate for atomically flat surfaces as otherwise a tip crash would be inevitable. One of its advantages is that it can be used at high scanning frequencies (up to 10 kHz). In comparison, the scanning frequency in the constant current mode is about 1 image per second or even per several minutes.



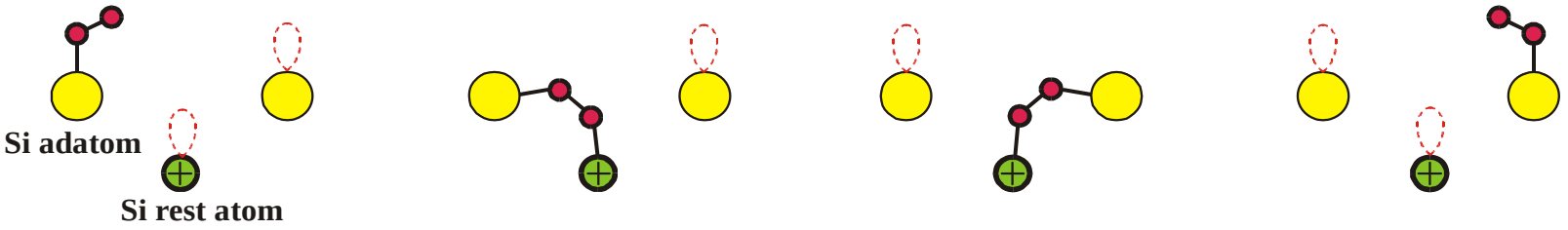
Site Hopping of O_2 Molecule on Si(111)-(7x7)

STM images

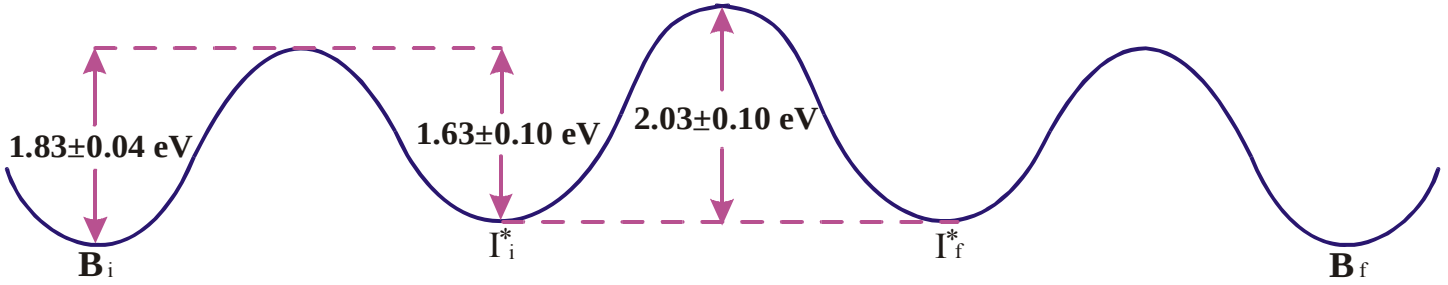


B_i I^*_i I^*_f B_f

Atomic model



Potential diagram



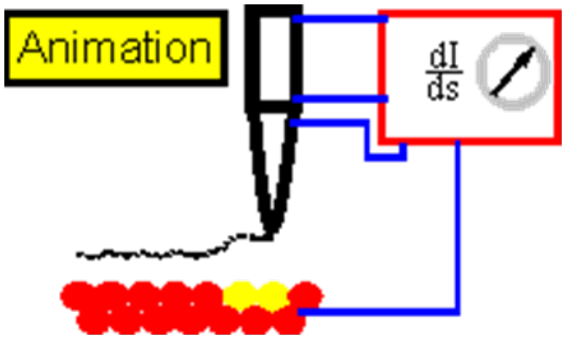
Scanning Tunneling Spectroscopy

1. Barrier Height Imaging

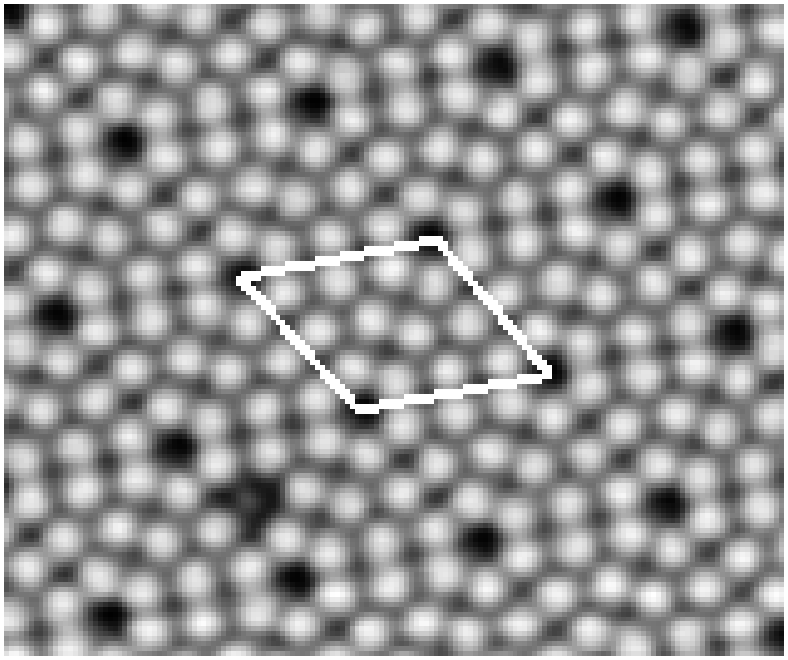
Up to now homogeneous surfaces were considered. If there is an inhomogeneous compound in the surface the work function will be inhomogeneous as well. This alters the local barrier height. Differentiation of tunneling current yields

$$\frac{d(\ln I)}{ds} \propto \sqrt{\Phi}$$

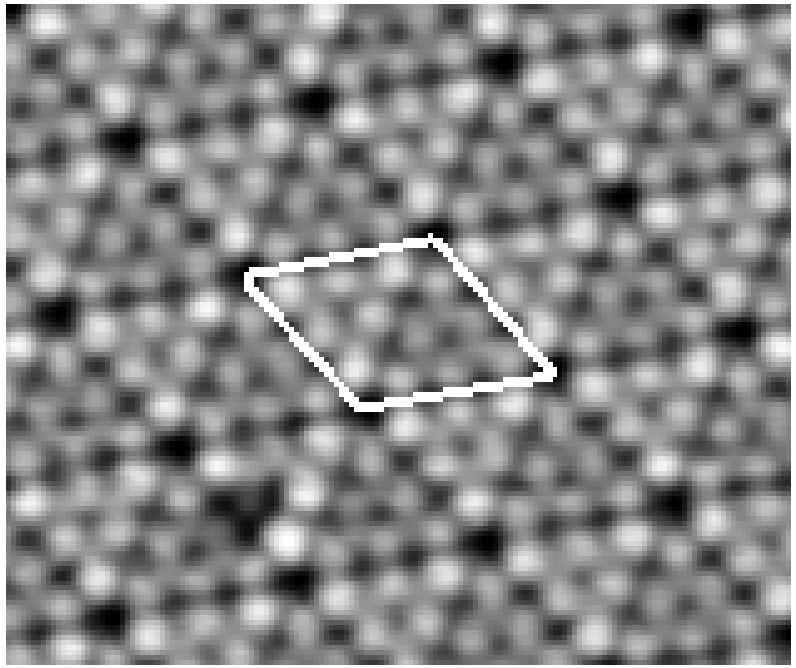
Thus the work function can directly be measured by varying the tip-sample distance, which can be done by modulating the current with the feedback turned on.



STM Images of Si(111)-(7×7)



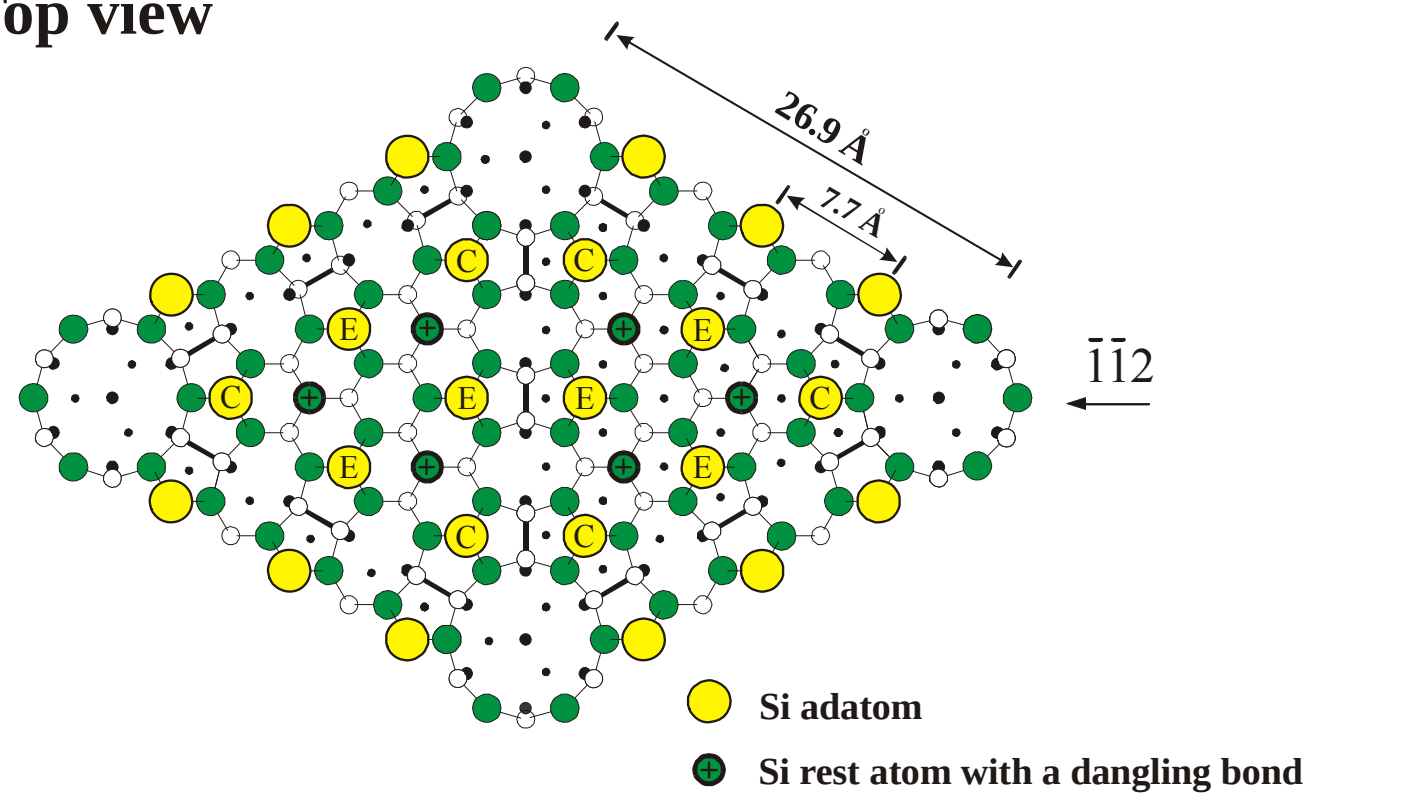
Empty-state image



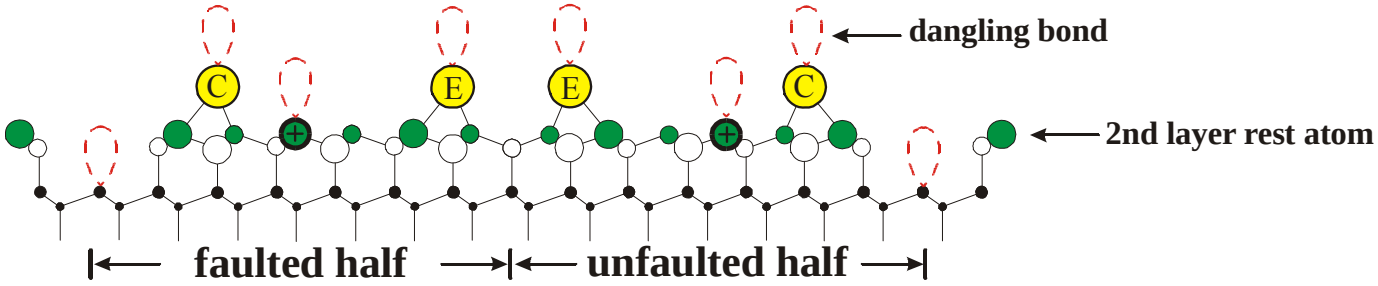
Filled-state image

Atomic Model of Si(111)-(7×7)

Top view

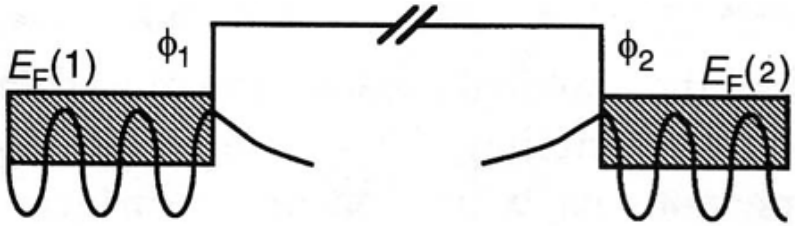


Side view

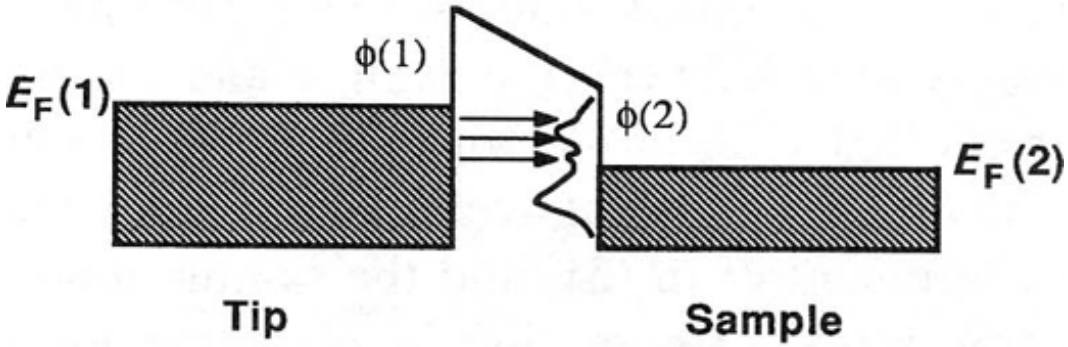


Electronic Structures at Surfaces

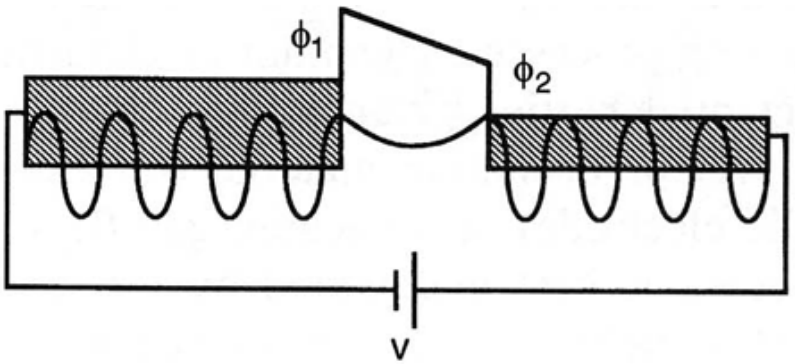
Not Tunneling



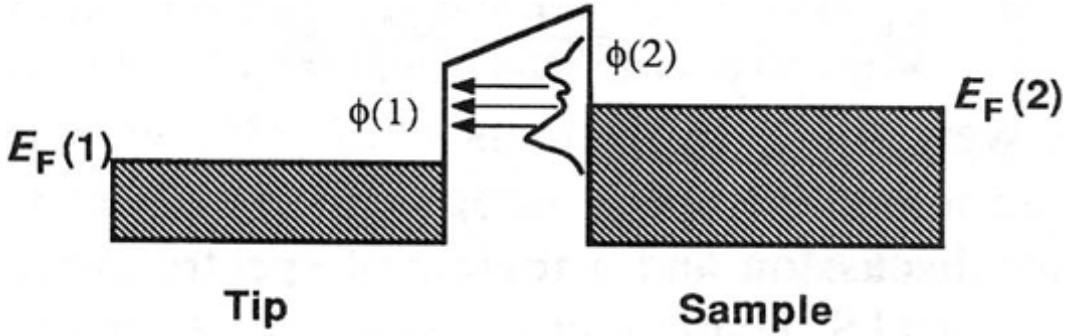
Empty-State Imaging



Tunneling



Filled-State Imaging



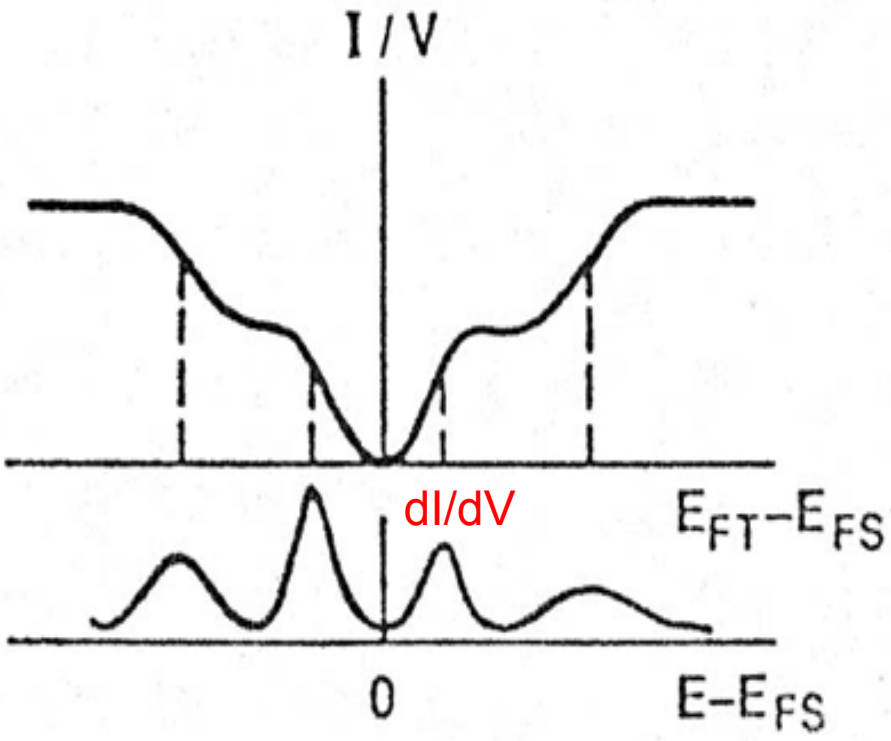
2. dI/dV imaging

If the matrix element and the density of states of the tip is nearly constant, the tunneling current can be estimated to

$$I \propto \int_0^{eV} \rho_{sa}\left(E_F - eV + \varepsilon\right) d\varepsilon$$

Differentiation yields the density of states

$$\frac{dI}{dV} \propto \rho_{sa}\left(E_F - eV\right)$$

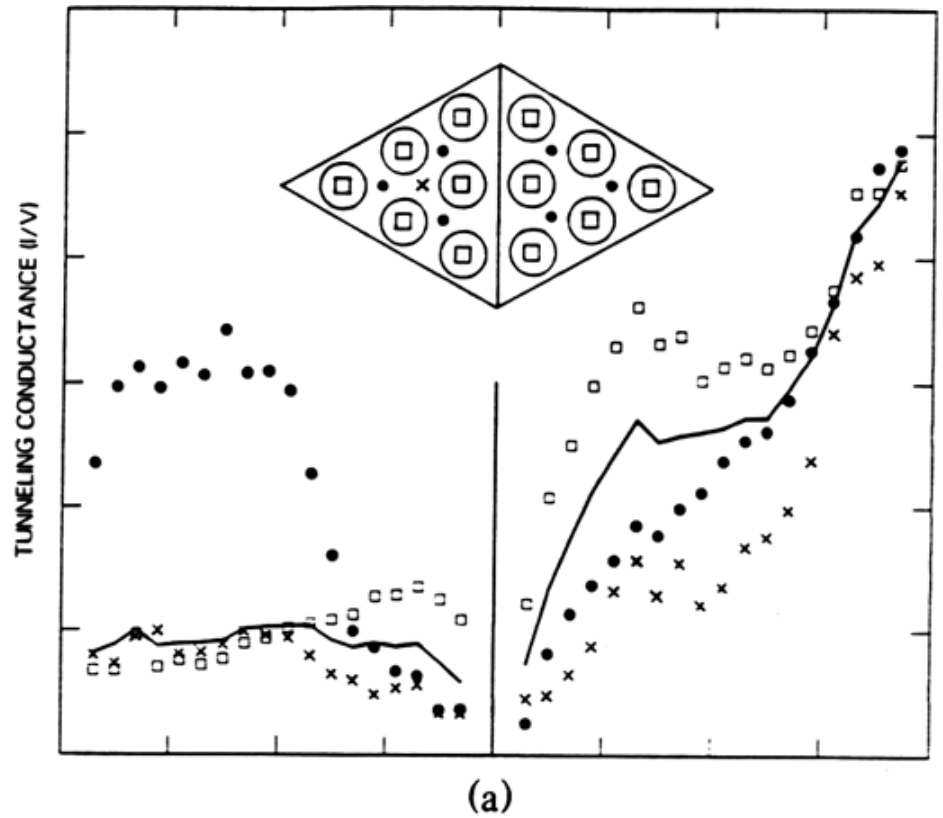


Density of state (DOS)

The mapping of surface density of states can be deduced by

- Modulation of the bias voltage (dI/dV imaging): The tip is scanned in the constant current mode to give a constant distance to the sample. A dither voltage of ~1k Hz is added to the bias voltage while the feedback loop remains active. A lock-in technique is employed to obtain the current change at the dither frequency.
- Current-Imaging Tunneling Spectroscopy (CITS): The tip is scanned in the constant current mode to give a constant distance to the sample. At each point the feedback loop is disabled and a current-voltage curve (I-V curve) is recorded.

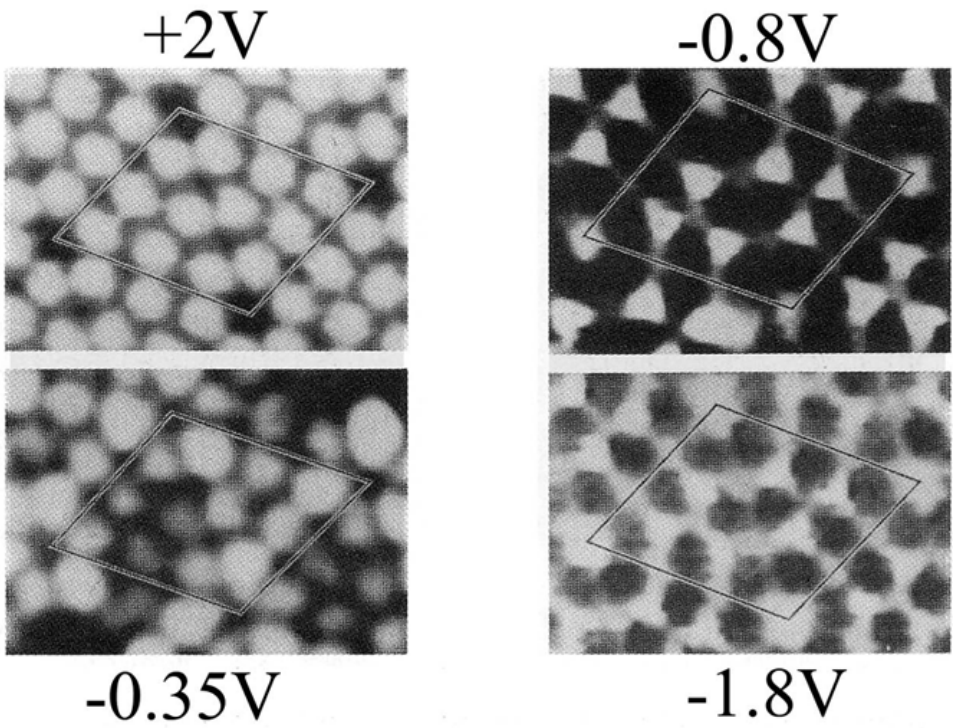
STS of Si(111)-(7x7)

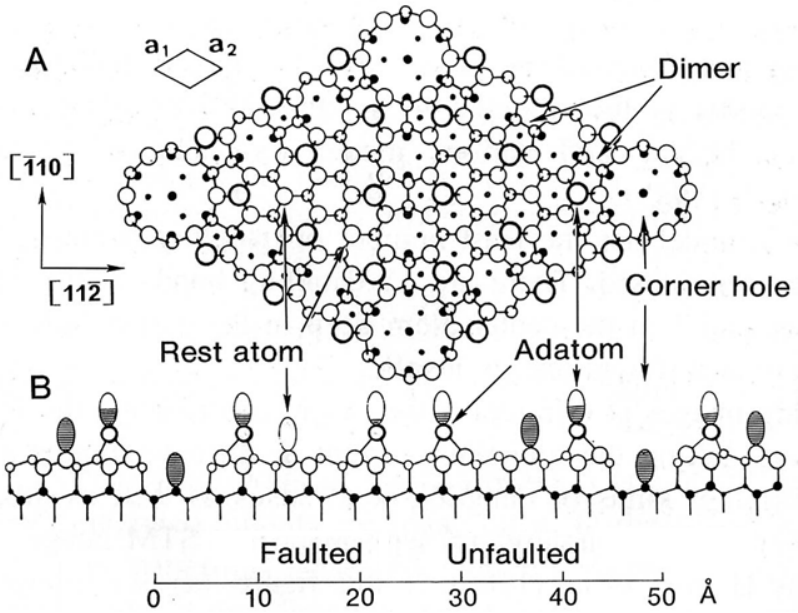


Science **234**, 304 (1986).

STS of Si(111)-(7x7)

topograph





1. Science **234**, 304-309 (1986).
2. Phys. Rev. Lett. **56**, 1972-1975 (1986).

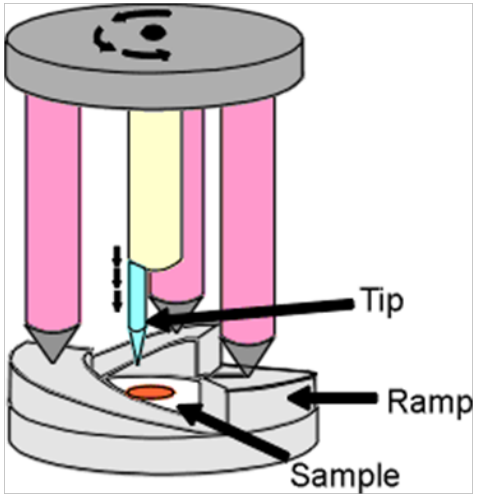
Technical Aspects

Demands:

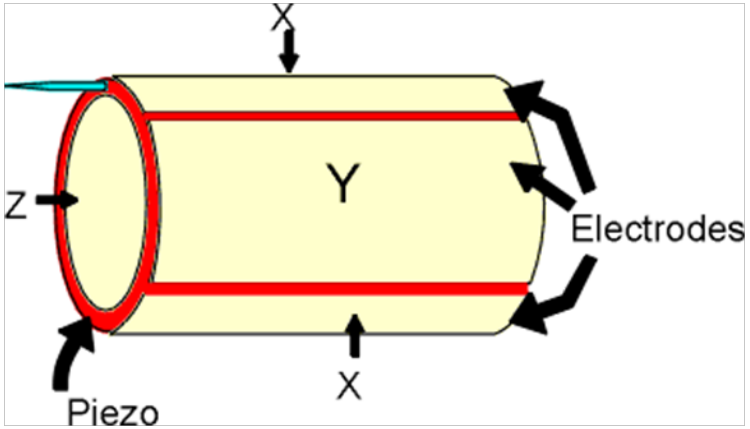
1. Controlling the tip-sample distance from a few mm down to 0.01Å
2. Exact lateral positioning
3. Stabilized tip-sample distance
4. Sharp tip
5. Measuring a current in the range of 0.01nA-50nA

Positioning

The large distance range the tip has to be controlled on makes it necessary to use two positioners: a coarse and a fine positioner. The fine positioner is also used as a scanner. Every fine positioner/scanner is made out of a piezocrystal or piezoceramic material.

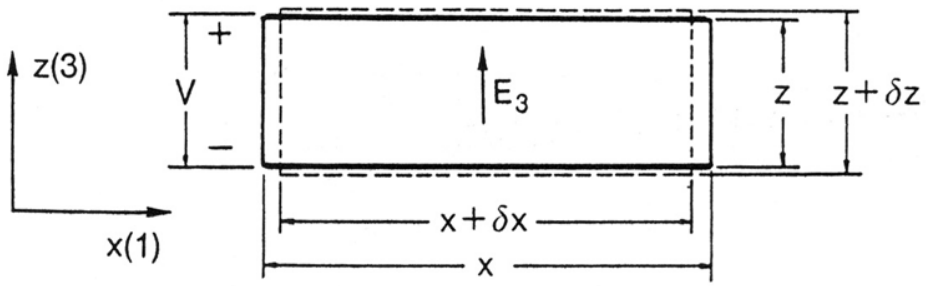


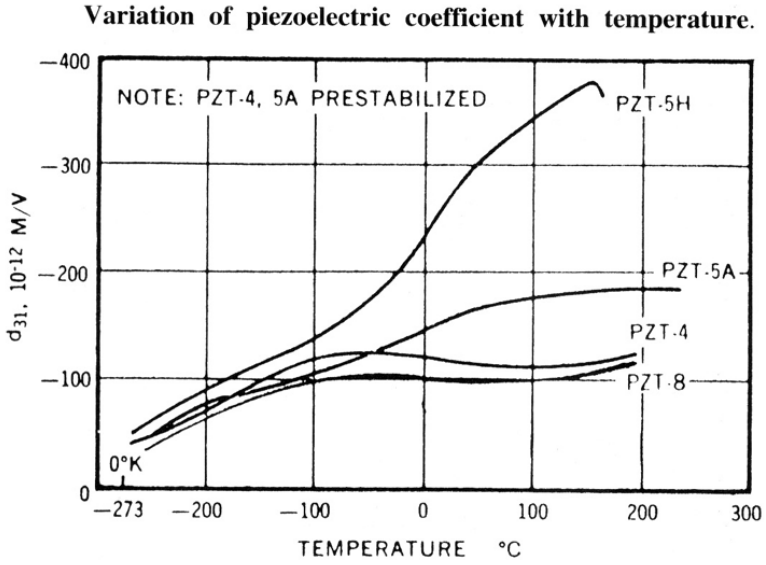
coarse positioner (beetle)



fine positioner/scanner

Piezoelectric Response





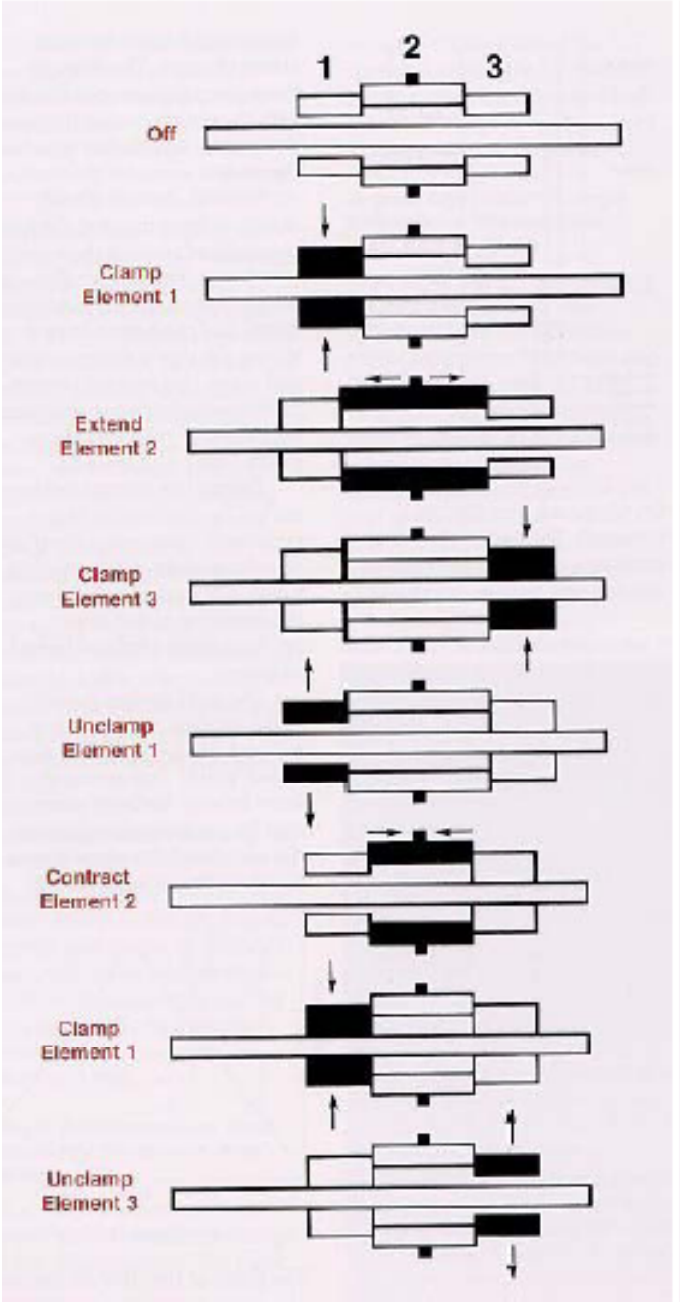
Strain: $S_1 = \delta x/x$, $S_3 = \delta z/z$

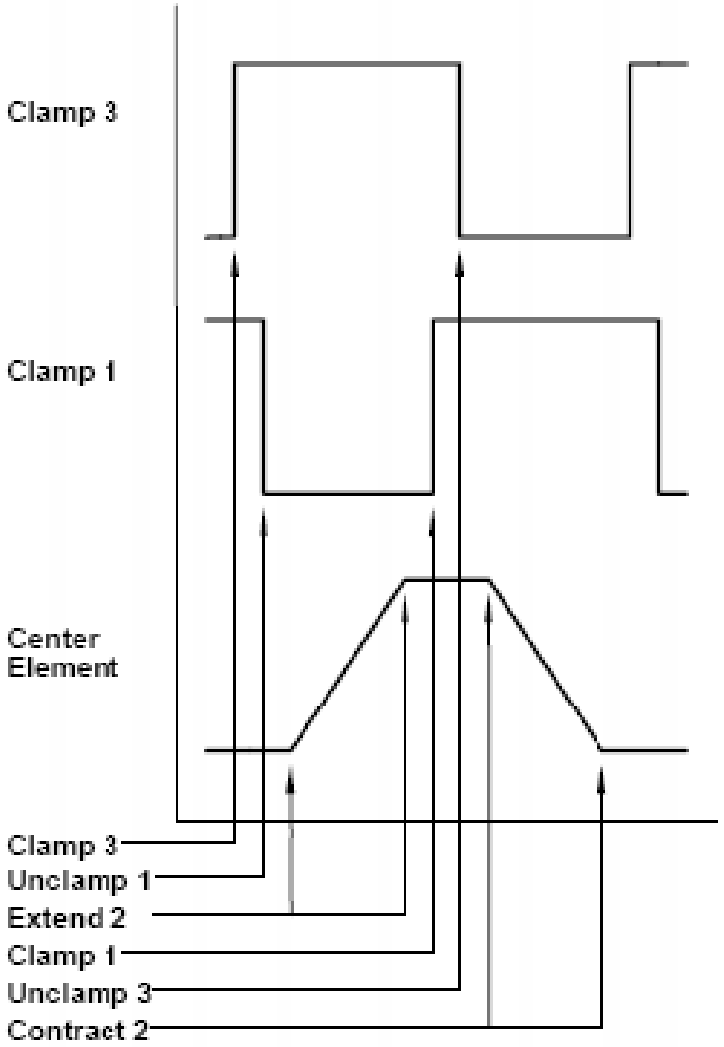
Electric field: $E_3 = V/z$

Piezoelectric Coeff.: $d_{33} = S_3/E_3$, $d_{31} = S_1/E_3$

Typical values for d_{31} ~ -1 Å/V, d_{33} ~ 3 Å/V.

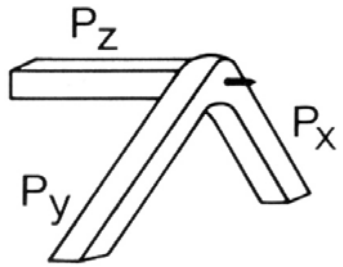
Inchworm Motor





Piezoelectric Scanner

Tripod scanner



$S_1 = \delta x/x = d_{31}E_3 = d_{31}V/z$

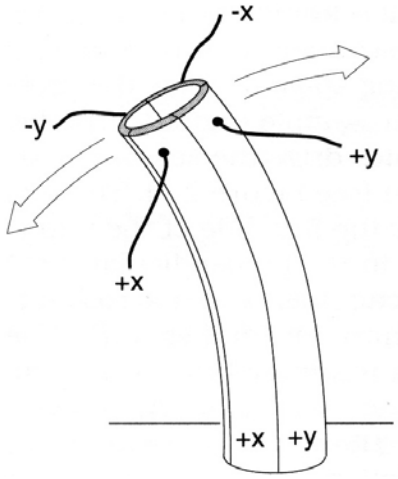
Piezoelectric Constant:

$K = dx/dV = d_{31}L/h$

Resonance Freq. for bending:

$f = 0.56\ \kappa C/L^2$, $\kappa = h/\sqrt{12}$

Tube scanner



Piezoelectric Constant:

$K = dx/dV = 2\sqrt{2}d_{31}L^2/\pi Dh$

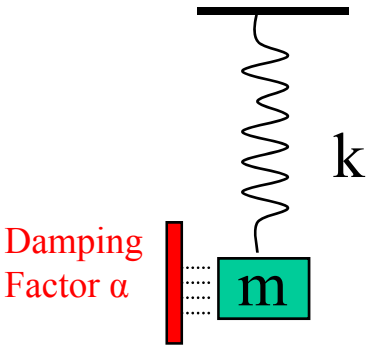
Resonance Freq. for bending:

$f = 0.56\ \kappa C/L2$, $\kappa = (D^2 + d^2)^{1/2}/8$

Vibration Isolation

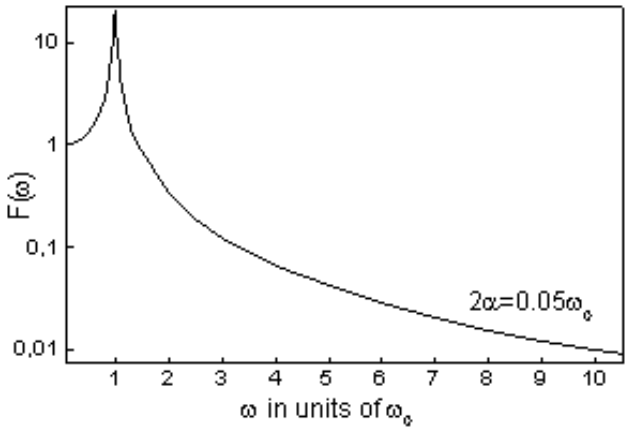
The tip-sample distance must be kept constant within 0.01Å to get good atomic resolution. Therefore it is absolutely necessary to reduce inner vibrations and to isolate the system from external vibrations.
Environmental vibrations are caused by:

- Vibration of the building 15 - 20 Hz
- Running people 2 - 4 Hz
- Vacuum pumps
- Sound



$$\omega_0 = \sqrt{k/m}$$

$$Q = \omega_0/2\alpha$$



Damping can be done by

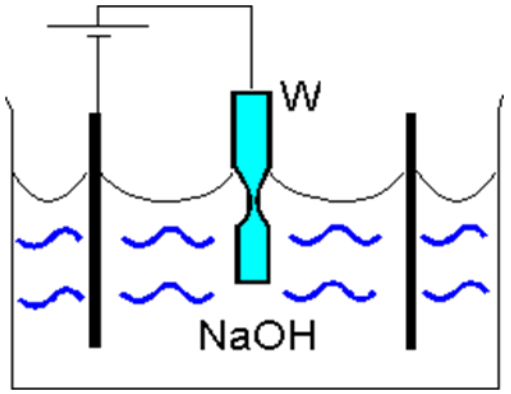
- Suspension with springs (including additional eddy current dampers)
- Stacked plate systems
- Pneumatic systems

Tip

The tip is the trickiest part in the STM experiment. It needs a small curvature to resolve coarse structures. For atomic resolution a minitip with a one atomic end is necessary. Tips typically are made out of tungsten, platinum or a Pt-Ir wire.

A sharp tip can be produced by:

- Cutting and grinding
- Electrochemical etching

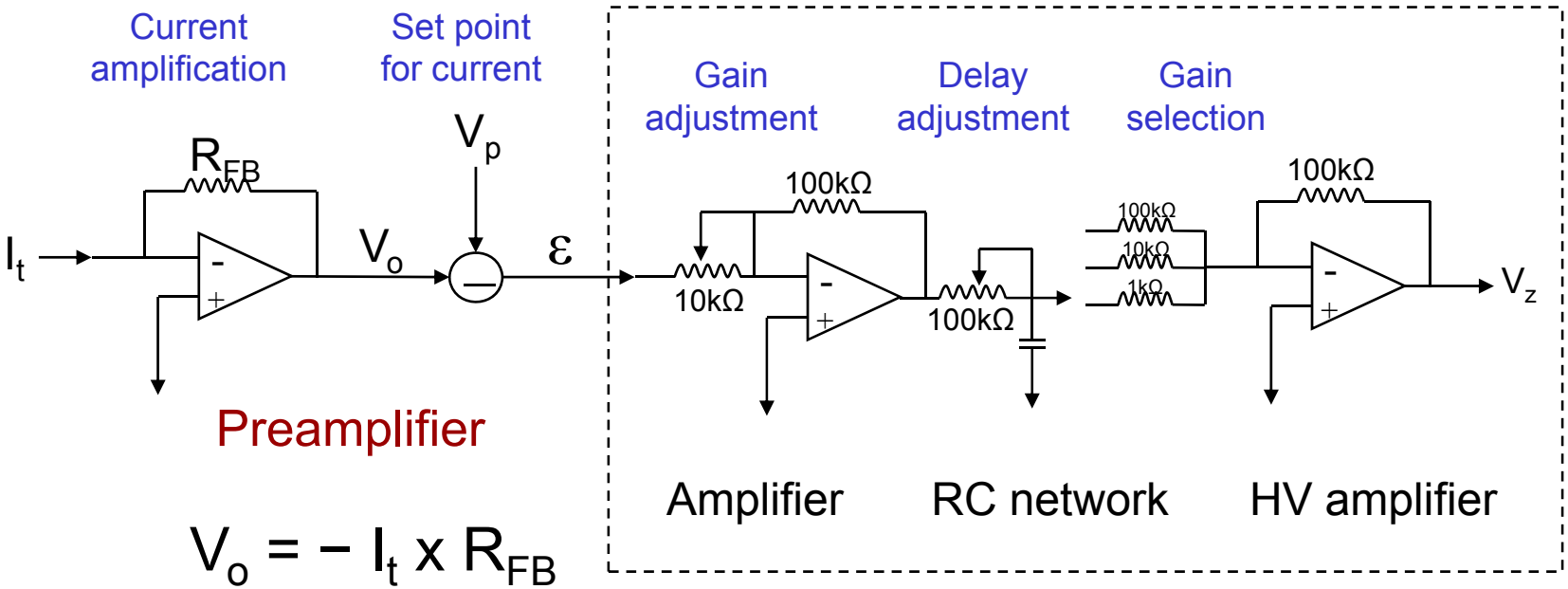


Most often the tip is covered with an oxide layer and contaminations from the etchant and is also not sharp enough. Thus other treatments to the tip, like annealing or field evaporation are necessary.

It is also possible to do tip-sharpening during tunneling.

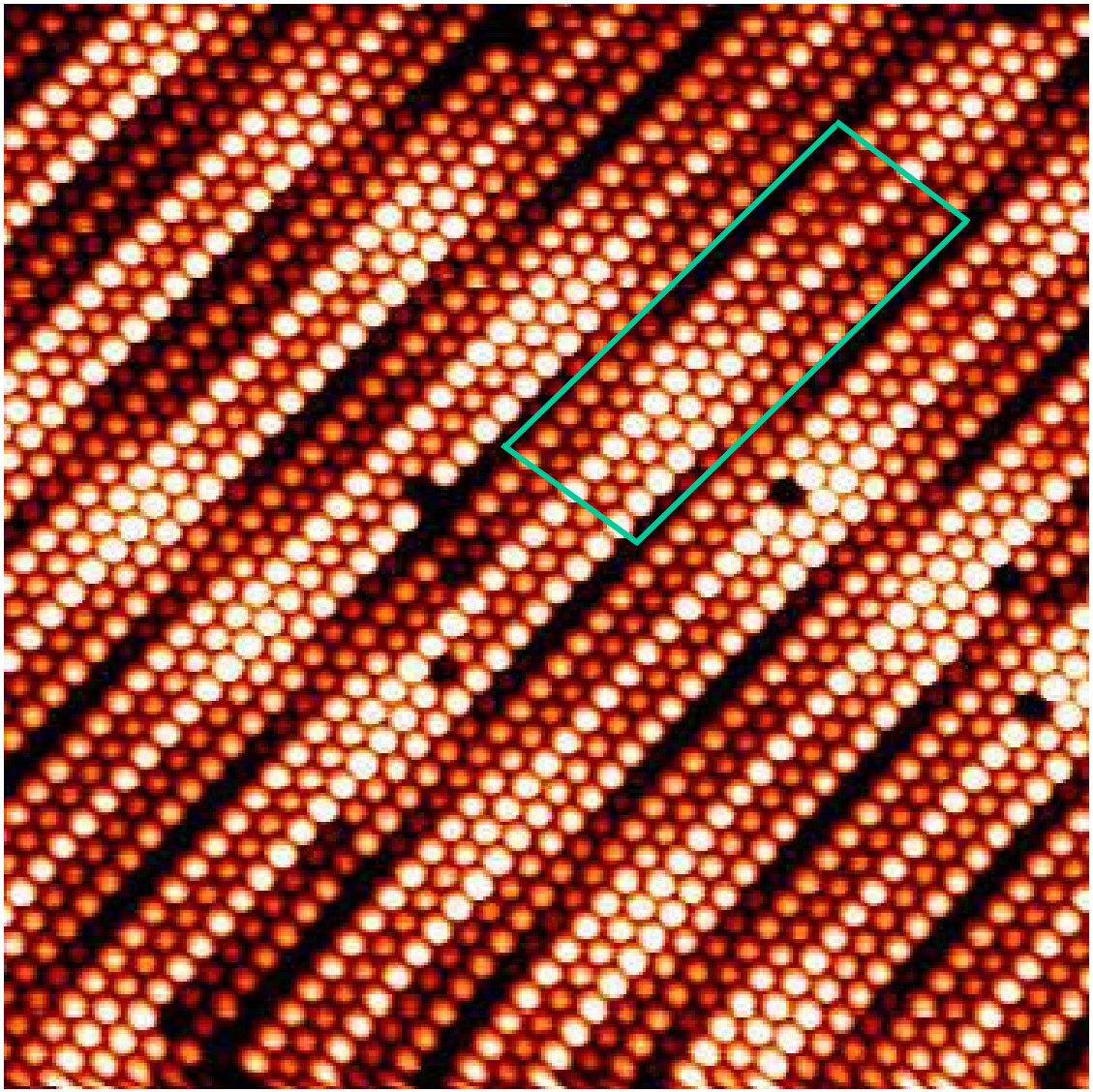
- Sudden rise of the bias voltage to about -7V (at the sample) for 2-4 scan lines. By this treatment some W atoms may walk to the tip apex due to the nonuniform electric field and form a nanotip.
- Controlled collision on Si surface.
  The tip may pick up a Si-cluster which forms a monoatomic apex with a $p_z$like dangling bond.

STM electronics and control

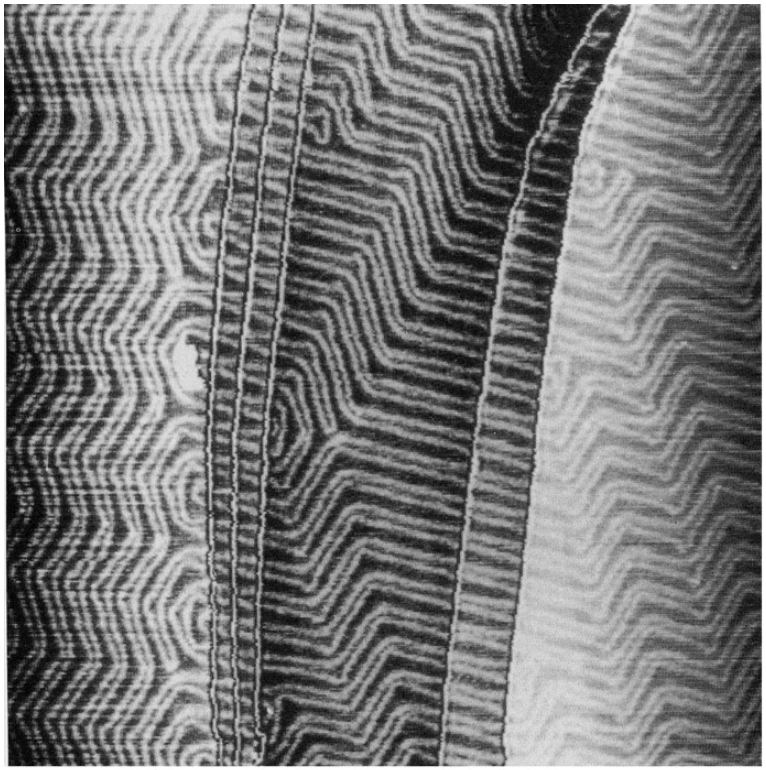


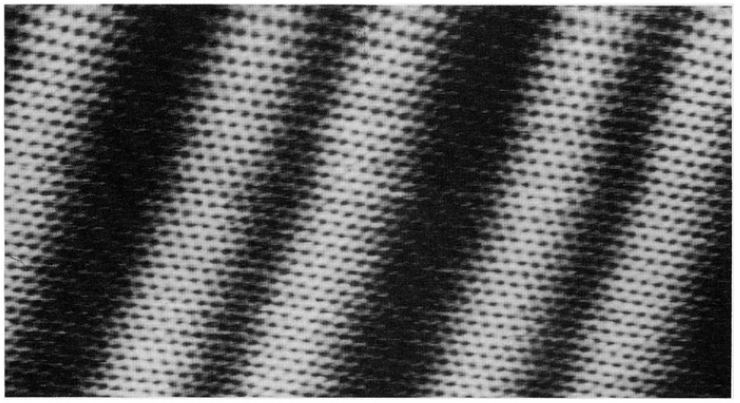
The tunneling current (0.01nA-50nA) is converted into a voltage by a current amplifier. To get a linear response with respect to the tunneling gap (the current is exponentially dependant on the tip-sample distance) the signal is processed by a logarithmic amplifier. The output of the logarithmic amplifier is compared with a predetermined voltage which is used as a reference current. The error signal is passed to feedback electronics, which applies a voltage to the z piezo to keep the difference between the current set point and the tunneling current small. Care has to be taken to keep the noise signal ratio on a low level. Also the response time of the feedback has to be minimized without loosing accuracy.

Atomic Structure of the Pt(001) Surface



Surface Science **306**, 10 (1994).





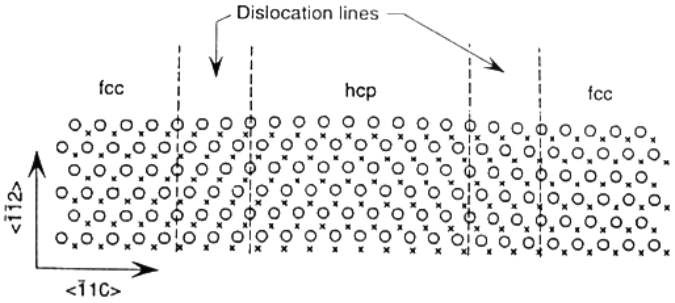
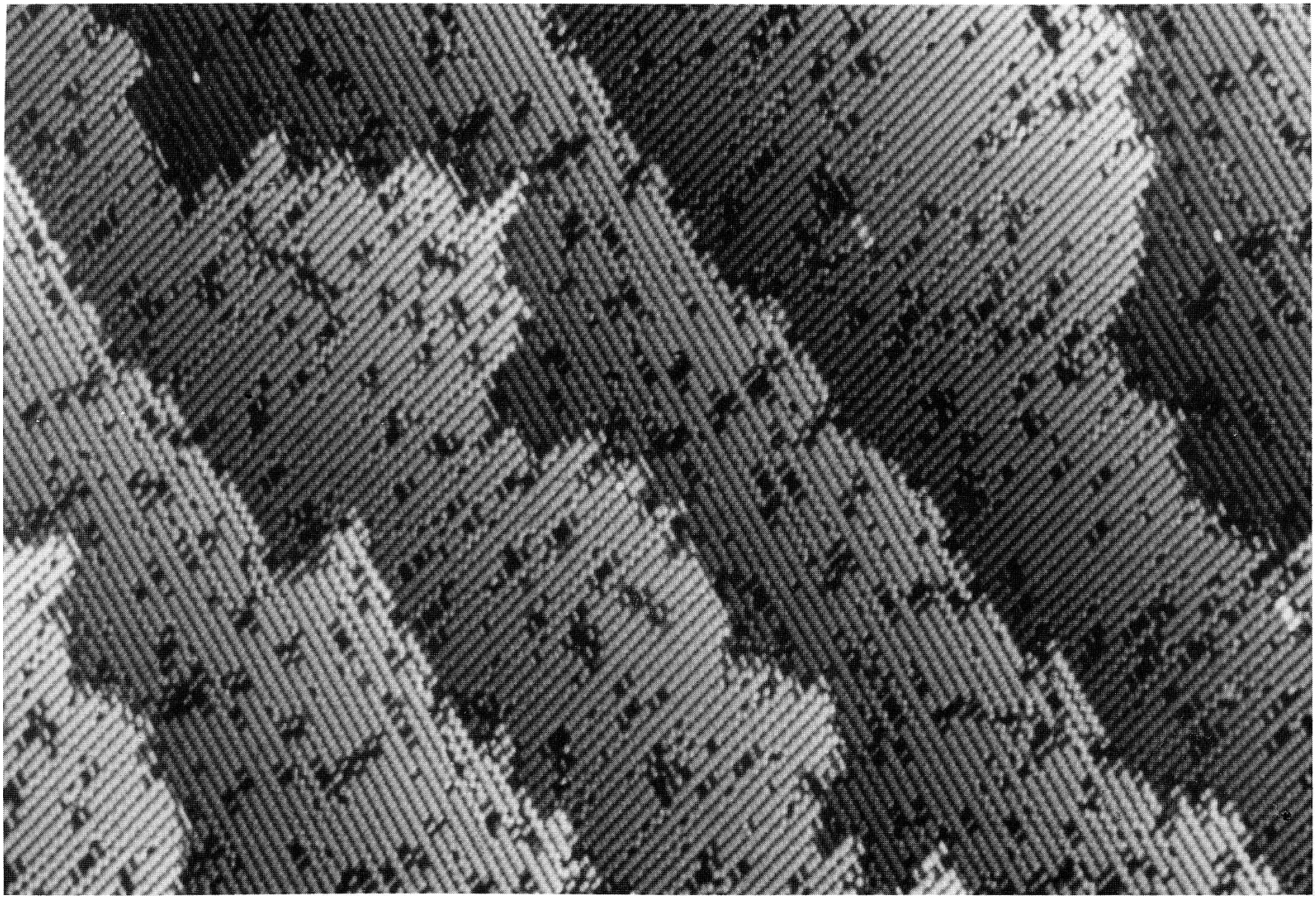


Fig. 1. In-plane structure of the Au(111) surface with a $22 \times \sqrt{3}$ reconstruction. The circles and crosses correspond to atoms in the first and second surface layers, respectively. Surface atoms in both sides of the figure lie on fcc sites, whereas atoms in the center of the figure lie on hcp sites. The domain walls (dislocation lines) involve atoms in bridge sites.

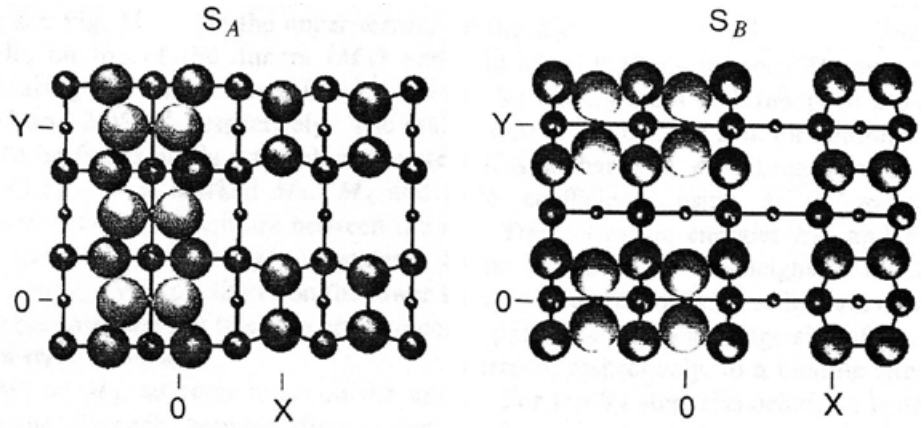
Large-scale image of the Au(111)-$22\times\sqrt{3}$ reconstruction. The Au(111) surface reconstructs at room temperature to form a $22\times\sqrt{3}$ structure, which has a two-fold symmetry. On a large scale, three equivalent orientations for this reconstruction coexist on the surface. Furthermore, on an intermediate scale, a herring-bone pattern is formed.

Science 258, 1763 (1992).

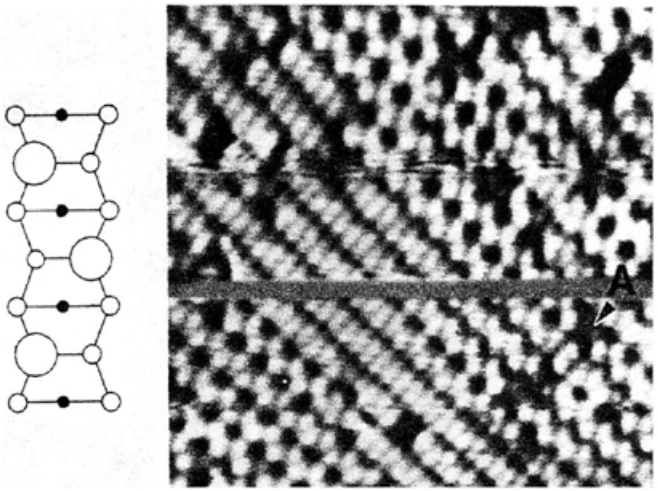
Atomic Structure of the Si(001) Surface



Si(001)-2x1 and 1x2



Si(001)-c(4x2)



Si(111)-(2x1)